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Novel Applications of Scanning Ultrafast Electron Microscopy (SUEM)

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Abstract

The Scanning Ultrafast Electron Microscope (SUEM) was used to image a wide array samples using a variety of standard and non-standard operating conditions on a custom system built in Org. 8942. The ability of this technique to produce high-quality images was assessed during this one year LDRD. To obtain details about the devices imaged, as well as the experimental details, please refer to the classified report from the project manager, Rich Dondero, or the NSP IA lead, Kristina Czuchlewski.

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